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## U.S. PATENT DOCUMENTS

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## FOREIGN PATENT DOCUMENTS

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**OTHER DOCUMENTS** (including Author, Title, Date, Pertinent pages, etc.)

11/05	1	PATENT ABSTRACTS OF JAPAN vol. 012, no. 177 (E-613), 05/1988 & JP 62 284600 (AGENCY OF IND SCIENCE & TECHNOL), 12/1987
	2	PATENT ABSTRACTS OF JAPAN vol. 011, no. 061 (E-483), 02/1987 & JP 61 220600 (NEC CORP), 09/1986
	3	PEDERSEN M et al.: "A silicon condenser microphone with polyimide diaphragm and backplate" SENSORS AND ACTUATORS A, vol. 63, no. 2, 10/1997, pp. 97-104
	4	SCHEEPER P R et al.: "FABRICATION OF SILICON CONDENSER MICROPHONES USING SINGLE WAFER TECHNOLOGY" JOURNAL OF MICROELECTROMECHANICAL SYSTEMS, vol. 1, no. 3, 09/1992, pp. 147-154
	5	THIELEMANN C et al.: "Capacitive silicon sensors for ultrasound" ACUSTICA-ACTA ACUSTICA, 07-08/1997, S. HIRZEL VERLAG, GERMANY, vol. 83, no. 4, pp. 715-720
11/05	6	MATTILA P et al.: "BANDWIDTH CONTROL OF AN ELECTROSTATIC ULTRASONIC TRANSDUCER" SENSORS AND ACTUATORS A, vol. A45, no. 3, 12/1994, pp. 203-208

\*Examiner

Date Considered

2/4/06

Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to application.

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**A. DEXTER TUGBANG**  
**PRIMARY EXAMINER**